

Title (en)
MICROELECTROMECHANICAL SWITCH AND METHOD FOR MANUFACTURING THE SAME

Title (de)
MEMS SCHALTER UND HERSTELLUNGSMETHODE HIERFÜR

Title (fr)
CONTACTEUR MEMS ET MÉTHODE DE PRODUCTION

Publication
EP 3227895 A1 20171011 (EN)

Application
EP 14806648 A 20141204

Priority
EP 2014076610 W 20141204

Abstract (en)
[origin: WO2016086998A1] A MEMS switch comprises a first and a second contact arrangement having a side facing each other, the first and the second contact arrangement movable with respect to each other and configured for providing an electric contact in a first state and for not providing the electric contact in a second state. A first contact material is arranged at the side of the first contact arrangement. A second contact material is arranged at the side of the second contact arrangement. The side of the first and/or the side of the second contact arrangement comprises a recessed region and a projected region projected with respect to the recessed region, the projected region and the recessed region separated from each other by a tear-off edge. The first and/or the second contact material is arranged at the recessed region and at the projected region of the respective side. The electric contact is provided between the first and the second contact material in the projected region of the sides and not provided in the recessed region in the first state.

IPC 8 full level
H01H 1/00 (2006.01); **H01H 59/00** (2006.01)

CPC (source: EP)
H01H 1/0036 (2013.01); **H01H 59/0009** (2013.01); **H01H 2001/0052** (2013.01); **H01H 2001/0078** (2013.01)

Citation (search report)
See references of WO 2016086998A1

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